

## EAST Search History

| Ref # | Hits | Search Query  | DBs   | Default Operator | Plurals | Time Stamp       |
|-------|------|---|---|------------------|---------|------------------|
| L8    | 289  | (205/662.ccls. 204/229.4. ccls.)  | US_PGPUB;<br>USPAT;<br>USOCR; EPO;<br>JPO;<br>DERWENT;<br>IBM_TDB | OR               | ON      | 2009/01/27 15:34 |
| S1    | 2    | "5807165".pn.   | US_PGPUB;<br>USPAT;<br>USOCR; EPO;<br>JPO;<br>DERWENT;<br>IBM_TDB | OR               | ON      | 2007/09/17 10:21 |
| S2    | 2    | "20040060814".pn.   | US_PGPUB;<br>USPAT;<br>USOCR; EPO;<br>JPO;<br>DERWENT;<br>IBM_TDB | OR               | ON      | 2007/09/17 10:22 |
| S3    | 3    | "6706158".pn.   | US_PGPUB;<br>USPAT;<br>USOCR; EPO;<br>JPO;<br>DERWENT;<br>IBM_TDB | OR               | ON      | 2007/09/17 10:31 |
| S4    | 55   | intel.as. and ("204" "205"). clas.  | US_PGPUB;<br>USPAT;<br>USOCR; EPO;<br>JPO;<br>DERWENT;<br>IBM_TDB | OR               | ON      | 2007/09/17 10:24 |
| S5    | 60   | ((electrochemical<br>electrochemically<br>electrolytic electrolytically)<br>adj (mechanical<br>mechanically) adj (polish<br>polish\$3 planarize planariz<br>\$3 planarizat\$3)) and<br>@ad<"20010901" | US_PGPUB;<br>USPAT;<br>USOCR; EPO;<br>JPO;<br>DERWENT;<br>IBM_TDB | OR               | ON      | 2007/09/17 10:37 |

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| S6  | 11   | ((electrochemical electrochemically electrolytic electrolytically) adj (mechanical mechanically) adj (polish polish\$3 planarize planariz\$3 planarizat\$3)) and @ad< "20010901" and ((voltage potential) with (control control\$3))                                    | US_PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2007/09/17 11:09 |
| S7  | 1971 | ((chemical chemically) adj (mechanical mechanically) adj (polish polish\$3 planarize planariz\$3 planarizat\$3)) and @ad< "20010901" and ((voltage potential) with (control control\$3))  | US_PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2007/09/17 11:11 |
| S8  | 0    | ((chemical chemically) adj (mechanical mechanically) adj (polish polish\$3 planarize planariz\$3 planarizat\$3)) and @ad< "20010901" and (((voltage potential) with (control control\$3)) same (temperature and (flow adj rate) and (speed near2 (rotation rotat\$3)))) | US_PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2007/09/17 11:14 |
| S9  | 198  | ((chemical chemically) adj (mechanical mechanically) adj (polish polish\$3 planarize planariz\$3 planarizat\$3)) and @ad< "20010901" and (((voltage potential) with (control control\$3)) same (temperature))   | US_PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2007/09/17 11:15 |
| S10 | 22   | ((chemical chemically) adj (mechanical mechanically) adj (polish polish\$3 planarize planariz\$3 planarizat\$3).clm. and @ad< "20010901" and (((voltage potential) with (control control\$3)) same (temperature))   | US_PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2007/09/17 11:20 |

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| S11 | 6  | ((chemical chemically) adj (mechanical mechanically) adj (polish polish\$3 planarize planariz\$3 planarizat\$3).clm. and @ad< "20010901" and (((voltage potential) with (control control\$3)) same (flow adj rate))                                     | US_PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2007/09/17 11:25 |
| S12 | 68 | ((chemical chemically) adj (mechanical mechanically) adj (polish polish\$3 planarize planariz\$3 planarizat\$3).clm. and @ad< "20010901" and (((process process\$3 polish polish\$3) with (control control\$3)) same (flow adj rate))                   | US_PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2007/09/17 11:31 |
| S13 | 62 | ((chemical chemically) adj (mechanical mechanically) adj (polish polish\$3 planarize planariz\$3 planarizat\$3).clm. and @ad< "20010901" and (((process process\$3 polish polish\$3) with (control control\$3)) same (speed near2 (rotation rotat\$3))) | US_PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2007/09/17 11:35 |
| S14 | 10 | ((chemical chemically) adj (mechanical mechanically) adj (polish polish\$3 planarize planariz\$3 planarizat\$3).clm. and @ad< "20010901" and (((process process\$3 polish polish\$3) with (control control\$3)) same PID)                               | US_PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2007/09/17 11:35 |
| S15 | 4  | ("6176992"   "6402925"   "6413403"   "6464855"). PN.  | US_PGPUB; USPAT; USOCR                             | OR | ON | 2009/01/26 17:14 |

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| S16 | 4313 | <p>(((electrochemical electrochemically electrolytic electrolytically) adj (mechanical mechanically) adj (polish polish\$3 planarize planariz\$3 planarizat\$3)))</p> <p>electroprocess</p> <p>electroprocess\$3</p> <p>((electrochemical electrochemically electrolytic electrolytically) near2 (process process \$3))) and</p> <p>@ad&lt;"20010901" and</p> <p>((voltage potential current) with (control controll\$3 individual individually separate separate\$3))</p>   | US_PGPUB;<br>USPAT;<br>USOCR; EPO;<br>JPO;<br>DERWENT;<br>IBM_TDB | OR | ON | 2009/01/26<br>17:37 |
| S17 | 2067 | <p>(((electrochemical electrochemically electrolytic electrolytically) adj (mechanical mechanically) adj (polish polish\$3 planarize planariz\$3 planarizat\$3)))</p> <p>electroprocess</p> <p>electroprocess\$3</p> <p>((electrochemical electrochemically electrolytic electrolytically) near2 (process process \$3))) and</p> <p>@ad&lt;"20010901" and</p> <p>((voltage potential current) with (control controll\$3 individual individually separate separate\$3)) and (wafer workpiece substrate microelectronic)</p> | US_PGPUB;<br>USPAT;<br>USOCR; EPO;<br>JPO;<br>DERWENT;<br>IBM_TDB | OR | ON | 2009/01/26<br>17:39 |

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| S18 | 469  | <p>(((electrochemical electrochemically electrolytic electrolytically) adj (mechanical mechanically) adj (polish polish\$3 planarize planariz\$3 planarizat\$3)))</p> <p>((electroprocess electroporess\$3 ((electrochemical electrochemically electrolytic electrolytically) near2 (process process \$3))) with (wafer workpiece substrate microelectronic)) and @ad&lt; "20010901" and ((voltage potential current) with (control controll\$3 individual individually separate separate\$3))</p>  | US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2009/01/26 17:40 |
| S19 | 1210 | <p>(((electrochemical electrochemically electrolytic electrolytically) adj (mechanical mechanically) adj (polish polish\$3 planarize planariz\$3 planarizat\$3)))</p> <p>((electroprocess electroporess\$3 ((electrochemical electrochemically electrolytic electrolytically) near2 (process process \$3))) with (wafer workpiece substrate microelectronic)) and ((voltage potential current anode cathode electrode) with (individual individually separate separate\$3 segment segment\$3)))</p> | US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2009/01/26 18:05 |

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|-----|-----|--|---|----|----|---------------------|
| S20 | 877 | (((electrochemical<br>electrochemically<br>electrolytic electrolytically)<br>adj (mechanical<br>mechanically) adj (polish<br>polish\$3 planarize planariz<br>\$3 planarizat\$3)))<br>((electroprocess<br>electroprocess\$3<br>((electrochemical<br>electrochemically<br>electrolytic electrolytically)<br>near2 (process process<br>\$3))) with (wafer<br>workpiece substrate<br>microelectronic))) and<br>(((voltage potential<br>current anode cathode)<br>with (individual<br>individually separate<br>separate\$3 segment<br>segment\$3))) | US-PGPUB;<br>USPAT;<br>USOCR; EPO;<br>JPO;<br>DERWENT;<br>IBM_TDB | OR | ON | 2009/01/26<br>18:05 |
| S21 | 664 | S20 not S18  | US-PGPUB;<br>USPAT;<br>USOCR; EPO;<br>JPO;<br>DERWENT;<br>IBM_TDB | OR | ON | 2009/01/26<br>18:06 |
| S22 | 438 | (((electrochemical<br>electrochemically<br>electrolytic electrolytically)<br>adj (mechanical<br>mechanically) adj (polish<br>polish\$3 planarize planariz<br>\$3 planarizat\$3)))<br>((electroprocess<br>electroprocess\$3<br>((electrochemical<br>electrochemically<br>electrolytic electrolytically)<br>near2 (process process<br>\$3))) with (wafer<br>workpiece substrate<br>microelectronic))) and<br>(((voltage potential<br>current anode cathode)<br>with (individual<br>individually separate<br>separate\$3 segment<br>segment\$3))) | US-PGPUB  | OR | ON | 2009/01/27<br>10:41 |

1/27/2009 3:57:28 PM

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